

Updates on CHIPS Metrology Program

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CHIPS for America Vision





Economic Security

This act enables us to build more resilient supply chains for important components.



National Security

This act enables us to bring the most sophisticated technologies back to the U.S.

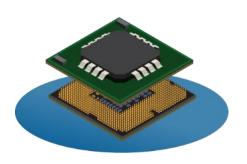


Future Innovation

Chips are key to the technologies and industries of the future, so we need to be at the forefront. This act will ensure long-term U.S. leadership in the sector.

CHIPS R&D Programs

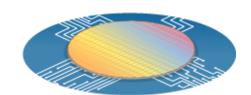




CHIPS National Semiconductor Technology Center (NSTC) Program



Natcast is a purpose-built nonprofit organization and operator of the NSTC consortium



CHIPS National Advanced Packaging Manufacturing Program (NAPMP)



CHIPS Manufacturing USA Program



CHIPS Metrology Program



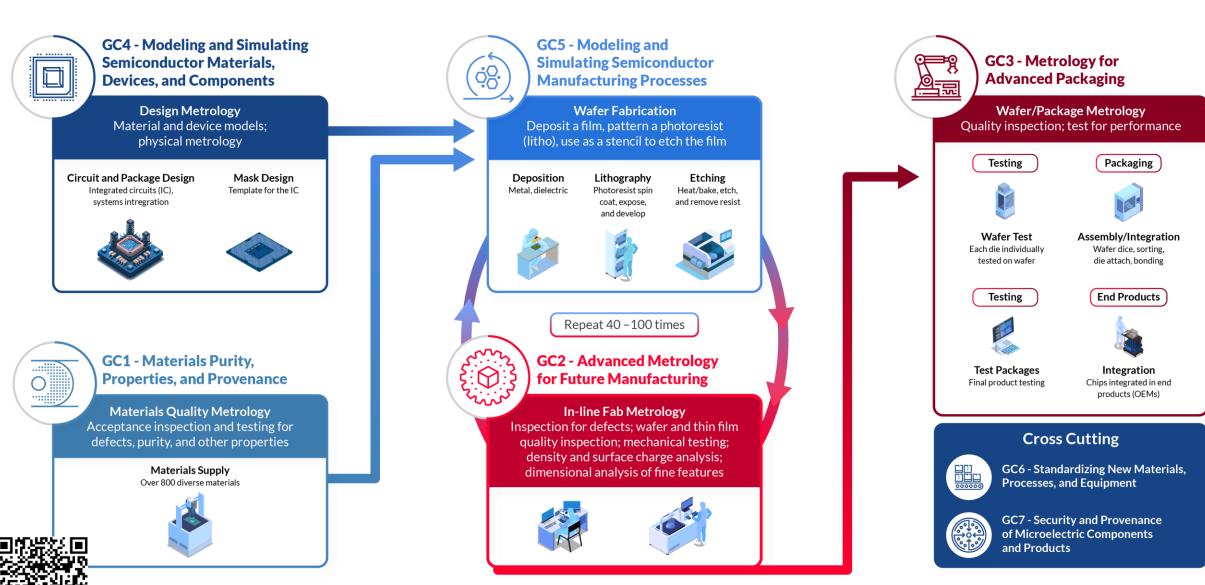
Workforce Initiatives





CHIPS Metrology Program Grand Challenges

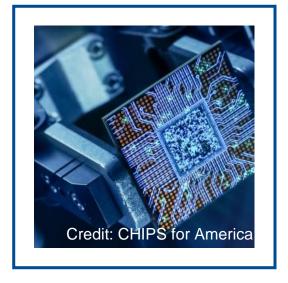




CHIPS Metrology Program: How Far We've Come











CHIPS Metrology R&D

CHIPS SBIR

CHIPS Metrology Community

Metrology Exchange to Innovate in Semiconductors

CHIPS Metrology R&D: How Far We've Come



Grand Challenge (GC) Funded Research Projects

- Over \$190 million in funding has been provided to more than 40 approved research projects in 6 Grand Challenges.
- Current projects are helping to develop new measurement instruments, measurement methods, and measurement-informed models and simulations for advanced microelectronics design and manufacturing.
- More information about the funded projects can be found on the CHIPS Metrology webpage. Additional
 project pages will be added this fall.

Industry and Academia Collaboration

- Research teams have proposed several distinct industry collaborators to provide materials and software and/or conduct joint research with researchers.
- Several collaborations with U.S. universities, nonprofit consortiums, research institutes, and associations related to the microelectronics industries have also been proposed.



CHIPS Metrology Small Business Innovation Research (SBIR) Program



Encourage domestic small businesses to engage in research and development (R&D) with the potential for commercialization.

- Stimulate commercialization of technological innovation from the private sector through Federal R&D funding.
- Foster participation in innovation by socially and economically disadvantaged small businesses.

Funding across multiple topics on research projects for:

- Critically needed measurement services, tools, and instrumentation.
- Innovative manufacturing metrologies.
- Novel assurance and provenance technologies.
- Advanced metrology research and development (R&D) testbeds.

SBIR Awardees

17 small businesses across 9 states





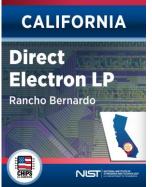
CHIPS SBIR Awardees



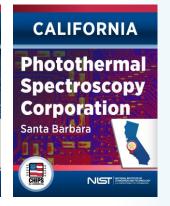






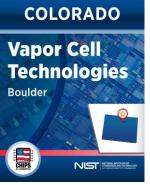












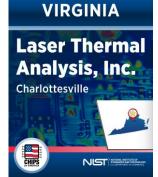
















CHIPS Metrology Community



The Community:

- Are engagement groups working to advance breakthrough measurements that are accurate, precise, and fit-for-purpose to produce microelectronic materials, devices, circuits, and systems.
- Facilitate collaborations to help improve data and knowledge sharing among all stakeholders in the semiconductor field.
- Help stakeholders inform the industry standards that are critical for enhancing U.S. economic or national security competitiveness to meet unprecedented demand for next generation networks.
- Help close the cultural and knowledge gaps between "fab," "lab," and equipment providers.



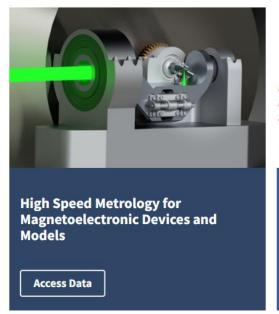


Metrology Exchange to Innovate in Semiconductors



METIS will make research and data available in a manner that guards intellectual property, protects U.S. security interests, is aligned with the approach used by NIST for access to research results, and is selfsustaining to meet future needs.











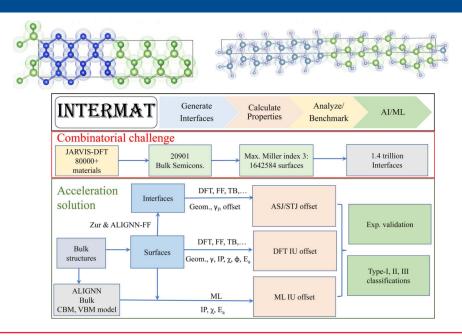
4.07 - Multiscale Modeling and Validation of Semiconductor Materials and Devices

Team member(s): Kamal Choudhary (642), Daniel Wines (642), Kevin Garrity (643), Brian DeCost (643), Lucas Hale (642), Eric Cockayne (643), Albert Davydov (642), Francesca Tavazza (643), Carrie Campbell (642)



Project Highlights:

- JARVIS-Leaderboard paper [1] enhances reproducibility and benchmarking for multi-scale modeling methods. The paper has 25k downloads.
- JARVIS-Tools software has half a million downloads and NIST-JARVIS. in general, has 150k users right now.
- The JARVIS dataset has close to 1 million downloads and 3k+ citations.
- InterMat project for semiconductor heterostructure design was published in Digital Discovery [2] and the code has been made publicly available.



Why Does it Matter?

- Enhance understanding of interfaces to improve device efficiency.
- Enhance understanding of defects to analyze device limitations.
- Multi-scale modeling tools accelerate advanced semiconductor device deployment.

Outcomes:

- Software tools and models can be used for evaluating materials and device configurations.
- Conversations with EDA software providers are ongoing to integrate InterMat in their software platform(s).

^{1.} K. Choudhary, et al. "JARVIS-Leaderboard: a large scale benchmark of materials design methods." npj Computational Materials 10.1 (2024): 93. doi: 10.1038/s41524-024-01259-w

^{2.} K. Choudhary and K. F. Garrity. "InterMat: accelerating band offset prediction in semiconductor interfaces with DFT and deep learning." Digital Discovery 3.7 (2024): 1365-1377. doi: 10.1039/D4DD00031E



Thank You!

Questions? Email: askchips@chips.gov

